

**S/N 09/471,460**

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Thomas A. Figura et al.	Examiner: Calvin Lee
Serial No.:	09/471,460	Group Art Unit: 2818
Filed:	December 22, 1999	Docket No.: 303.932US4
Title:	USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE	

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**AMENDMENT AND RESPONSE UNDER 37 CFR § 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

This paper responds to the Office Action mailed on February 14, 2007. Please amend the above-identified patent application as follows.